



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Paul B. Mirkarimi et al. Docket No. : CIL-10972

Serial No.: 10/086,614 Art Unit: 1762

Filed: March 1, 2002 Examiner: B. Pianalto

For : Ion-Assisted Deposition Techniques For

The Planarization Of Topological Defects

AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed December 9, 2003, please amend the above-referenced application as follows: